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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Masanobu IWASAKI, et al.

Application No.: 09/934,474

Filed: August 23, 2001



Customer Number: 20277

Confirmation Number: 8431

Group Art Unit: 3723

Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.

- ☒ No additional fee is required.
☐ Applicant is entitled to small entity status under 37 CFR 1.27
☐ Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	11	20	0	\$50.00 =	\$0.00
Independent Claims	3	3	0	\$200.00 =	\$0.00
Multiple dependent claims newly presented					\$0.00
Fee for extension of time					\$0.00
					\$0.00
Total of Above Calculations					\$0.00

- ☐ Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.
- ☒ The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

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Please recognize our Customer No. 20277 as our
correspondence address.



Docket No.: 050090-0334

PATENT

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In re Application of	:	Customer Number: 20277
Masanobu IWASAKI, et al.	:	Confirmation Number: 8431
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AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This Amendment, pursuant to 37 C.F.R. § 41.54, is submitted within two months from the decision on Appeal by the Honorable Board of Patent Appeals and Interferences mailed on March 29, 2007. Please amend the above-identified application as follows: